



Att. Docket No. 10191/1690

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Appl. Serial No. : 09/762,985 Confirmation No. 2674  
Title : DEVICE AND METHOD FOR  
ETCHING A SUBSTRATE USING  
AN INDUCTIVELY COUPLED PLASMA  
Applicant(s) : Volker BECKER et al.  
Filed : May 8, 2001  
TC/A.U. : 1763  
Examiner : Luz L. Alejandro Mulero  
Docket No. : 10191/1690  
Customer No. : 26646

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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on

Date: 6/28/2004  
Signature: [Signature]

**AARON C. DEDITCH**  
(33,865)

**AMENDMENT**

S I R:

In response to the Office Action mailed on March 3, 2004 (the three-month response date for which has been extended by one month from June 3, 2004 to July 3, 2004 by the accompanying Transmittal and Petition to Extend), please reconsider the above-identified application based on the following:

**Amendments to the Claims** are reflected in the listing of the claims which begins on page 2 of this paper.

**Remarks** begin on page 9 of this paper.